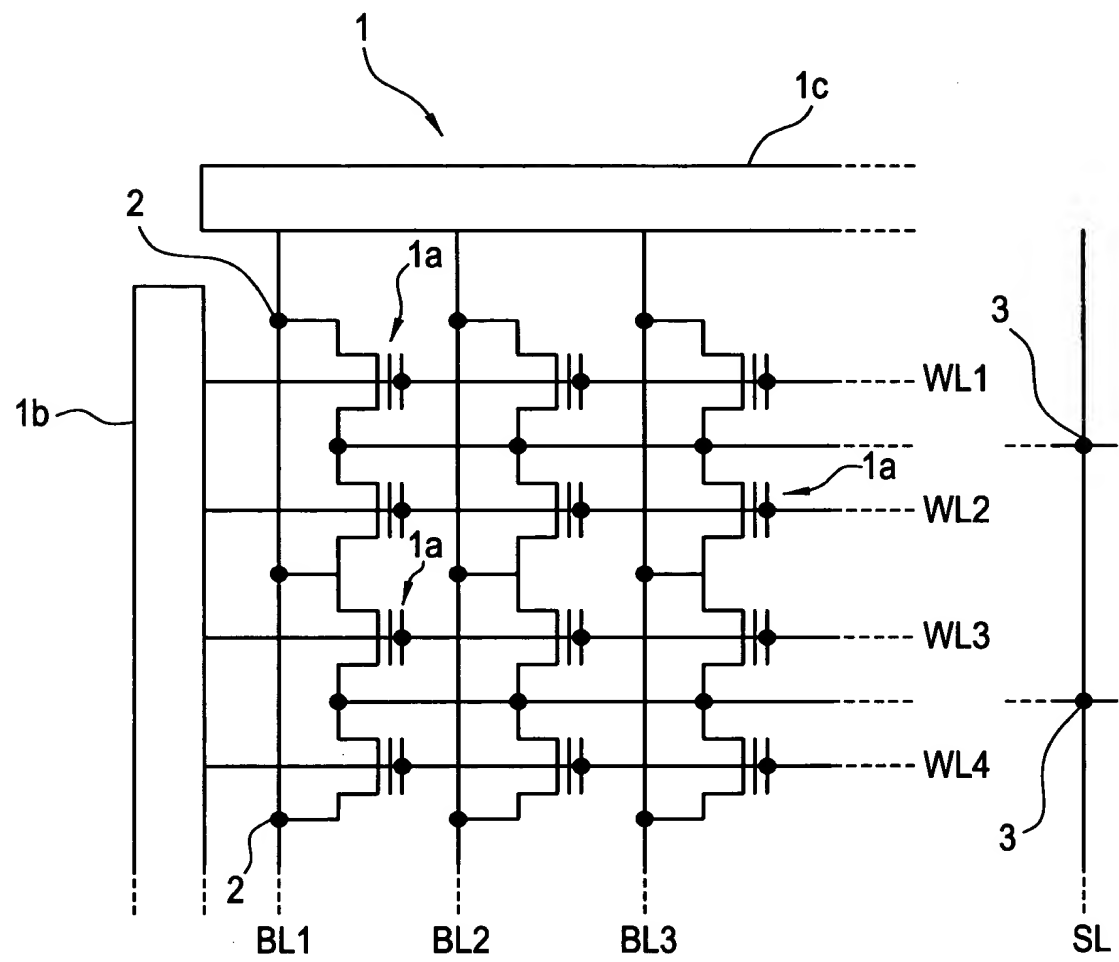


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FIG. 1

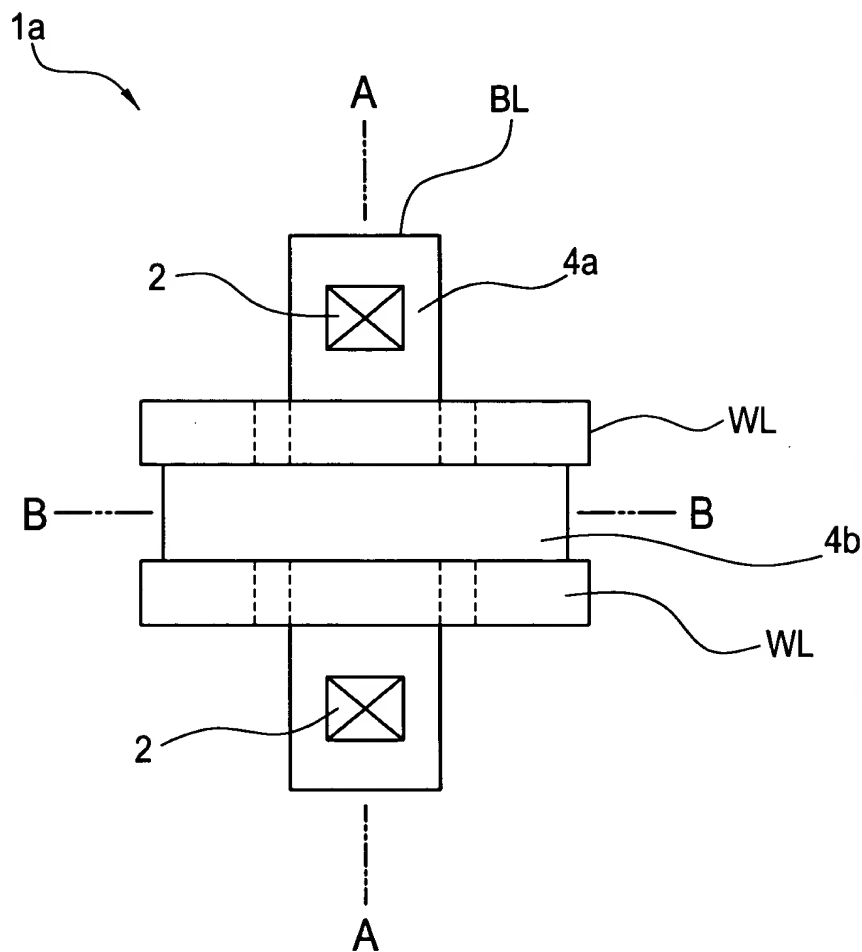


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2/20

FIG. 2



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3/20

FIG. 3A

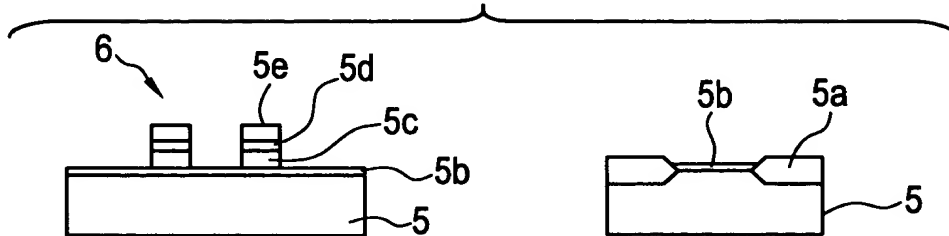


FIG. 3B

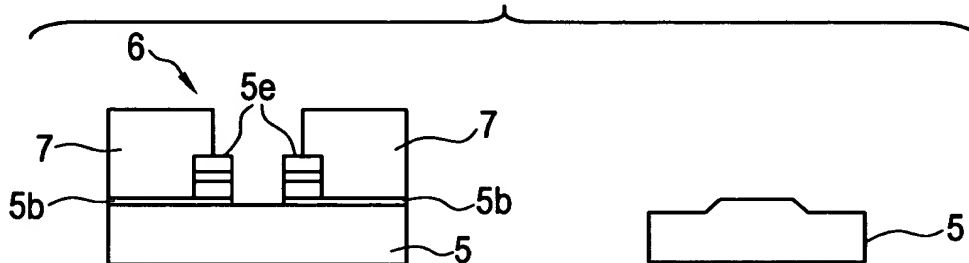


FIG. 3C

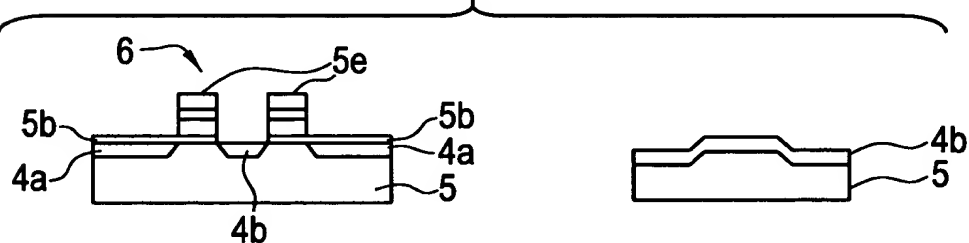


FIG. 3D

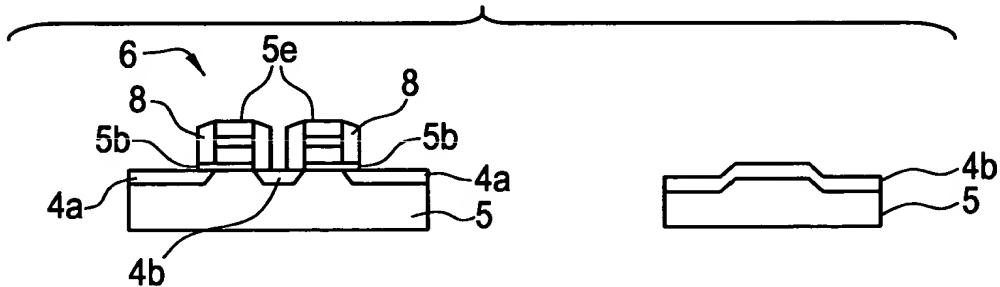
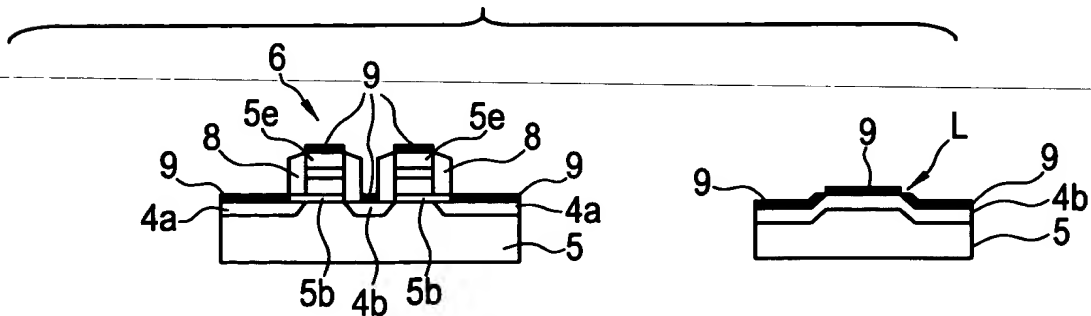


FIG. 3E

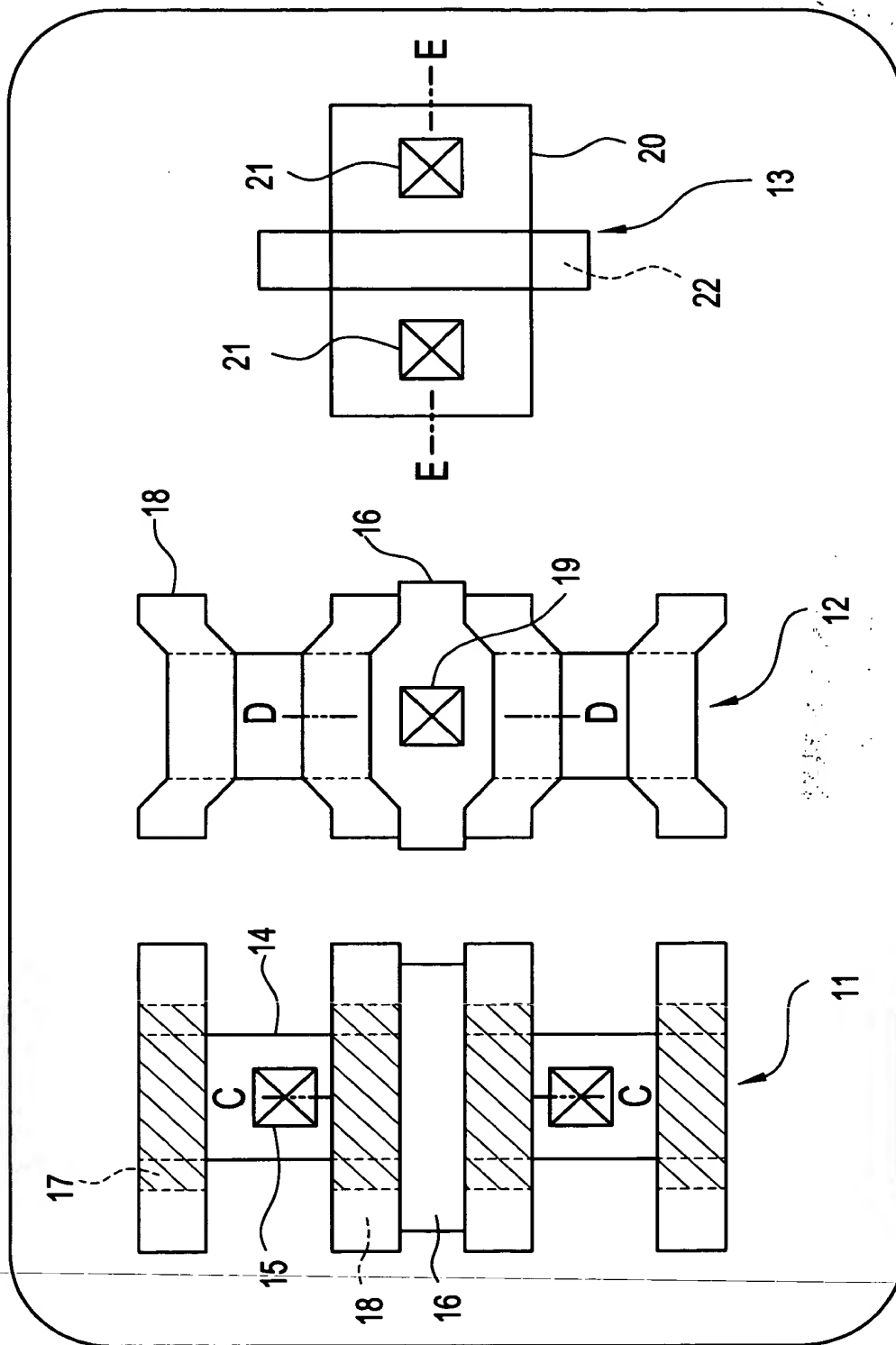


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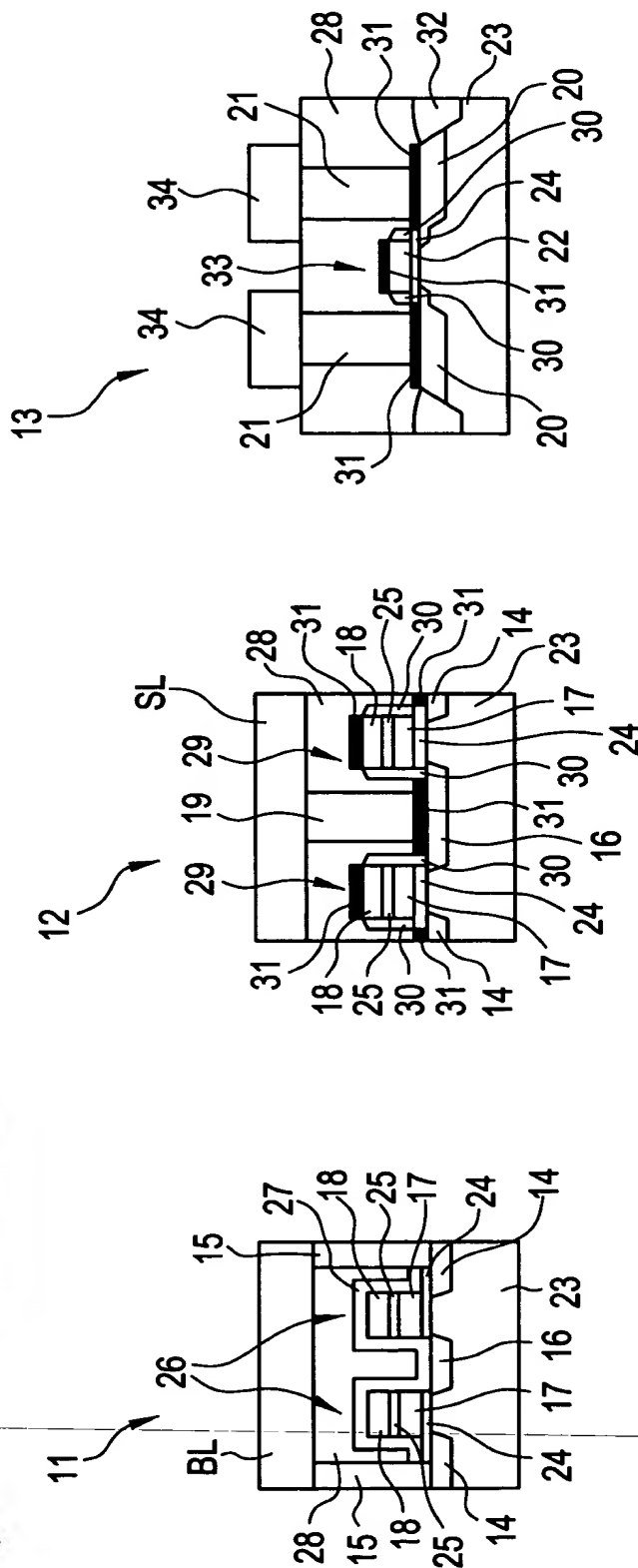
4/20

FIG. 4



5/20

FIG. 5



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6/20

FIG. 6A

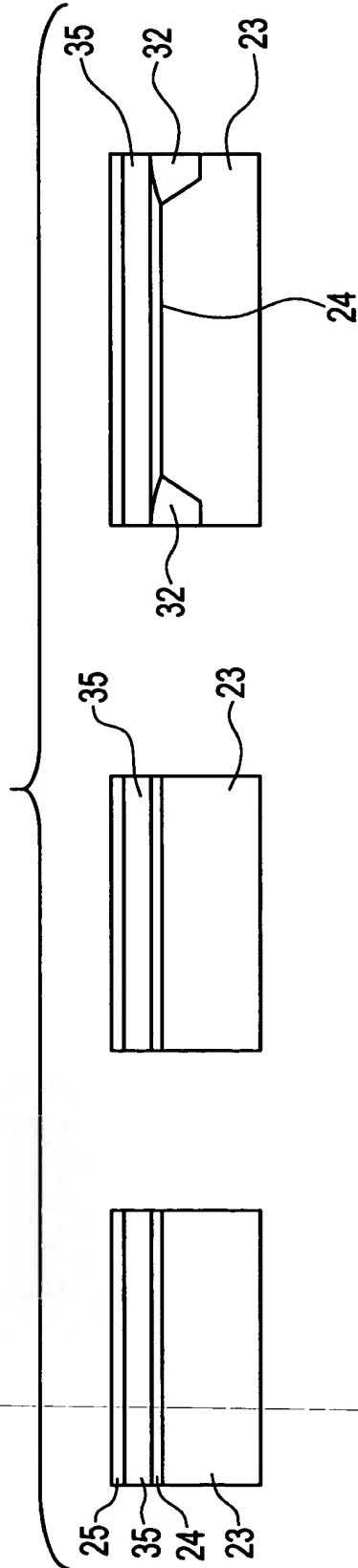
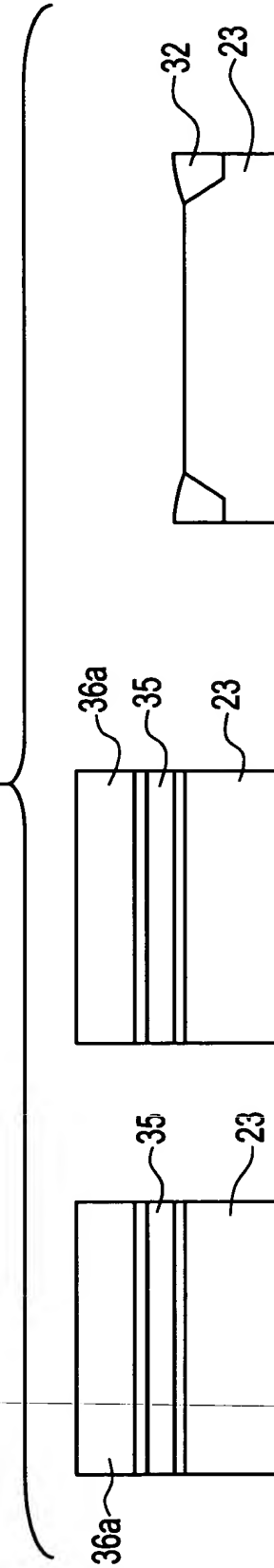


FIG. 6B



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7/20

FIG. 6C

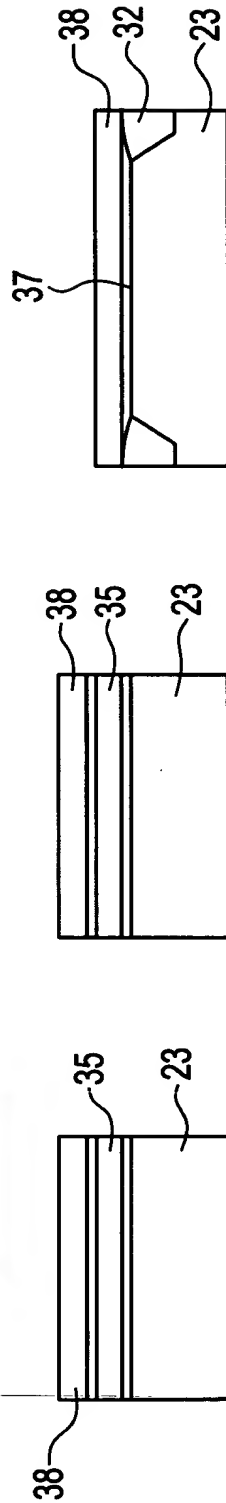
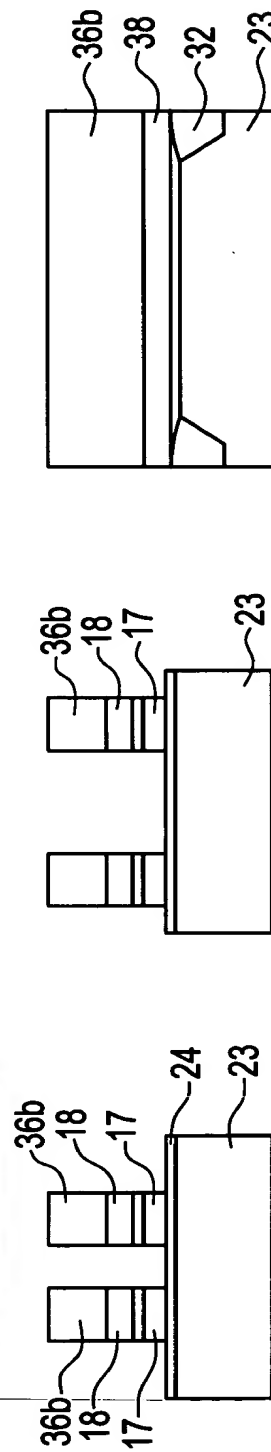


FIG. 6D



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8/20

FIG. 6E

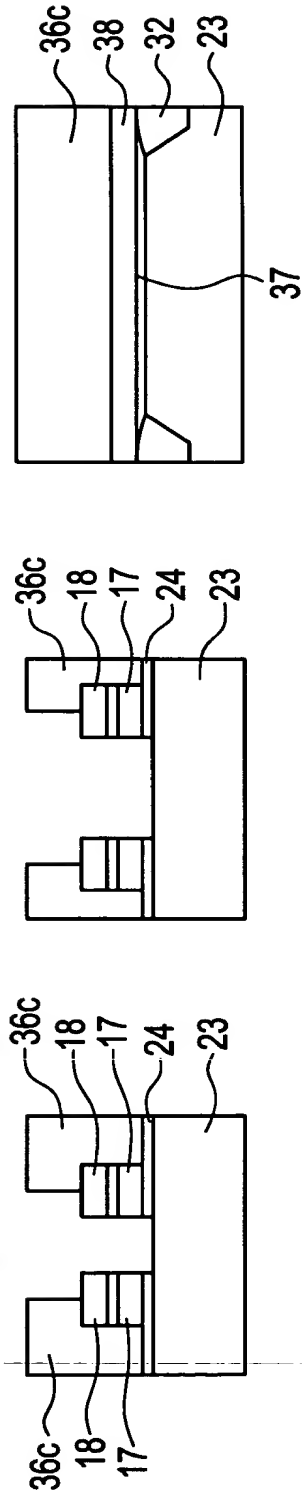
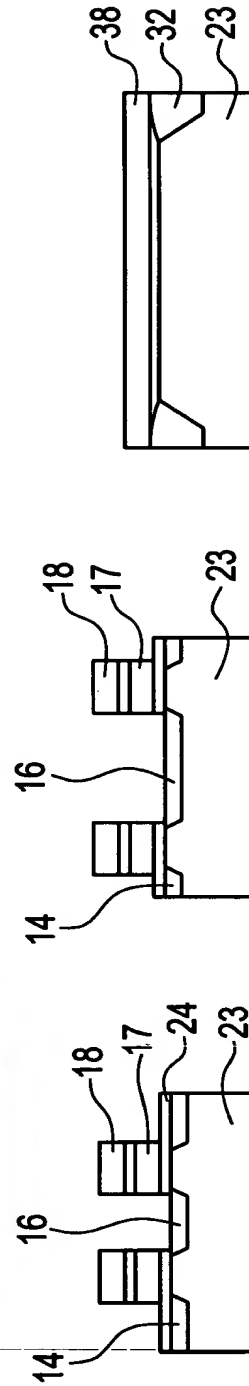


FIG. 6F





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9/20

FIG. 6G

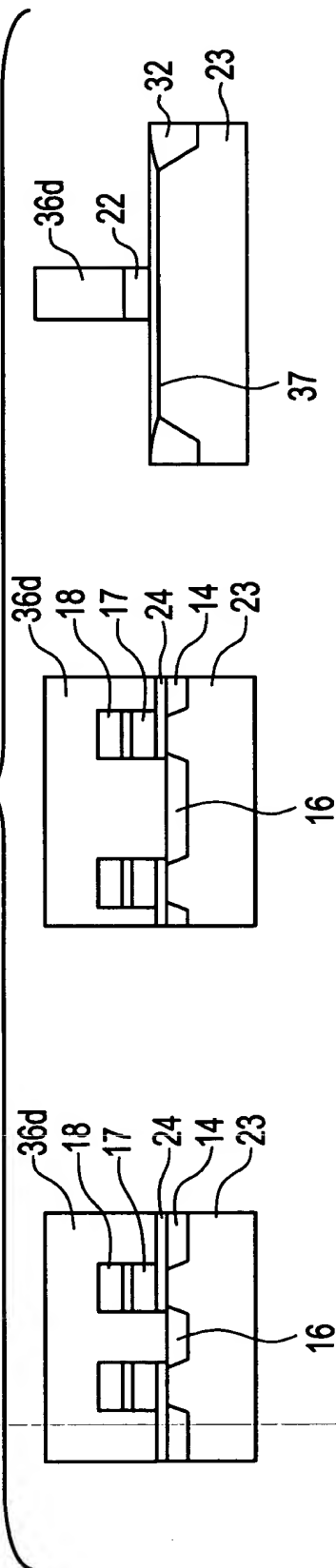
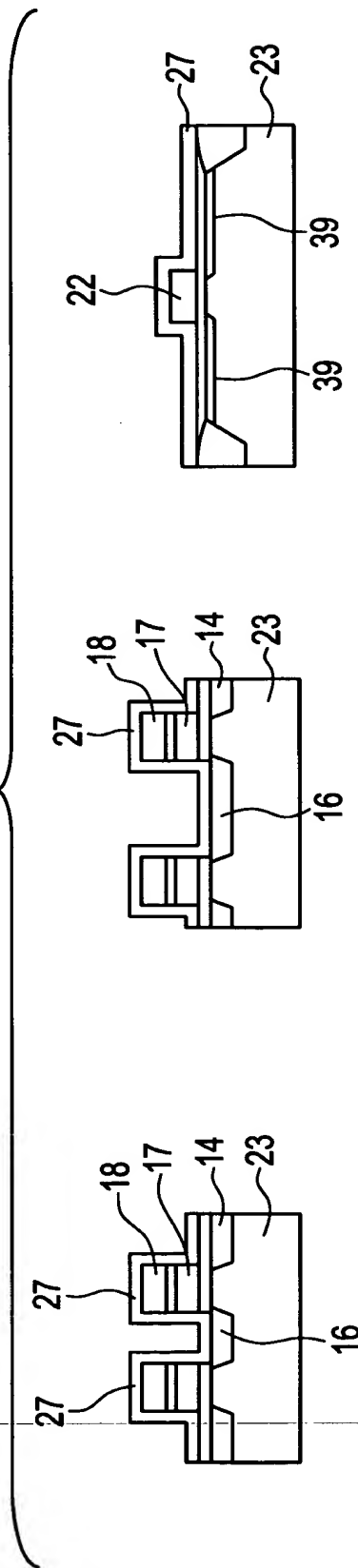


FIG. 6H



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10/20

FIG. 6I

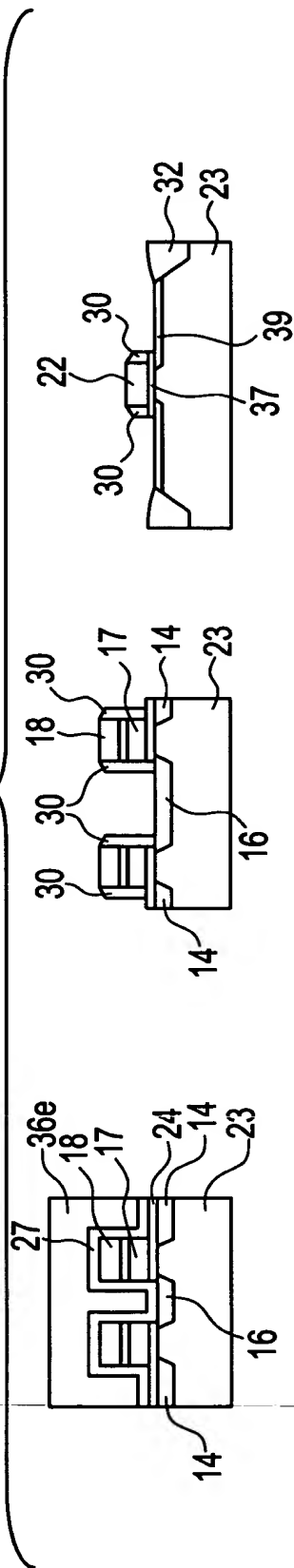


FIG. 6J

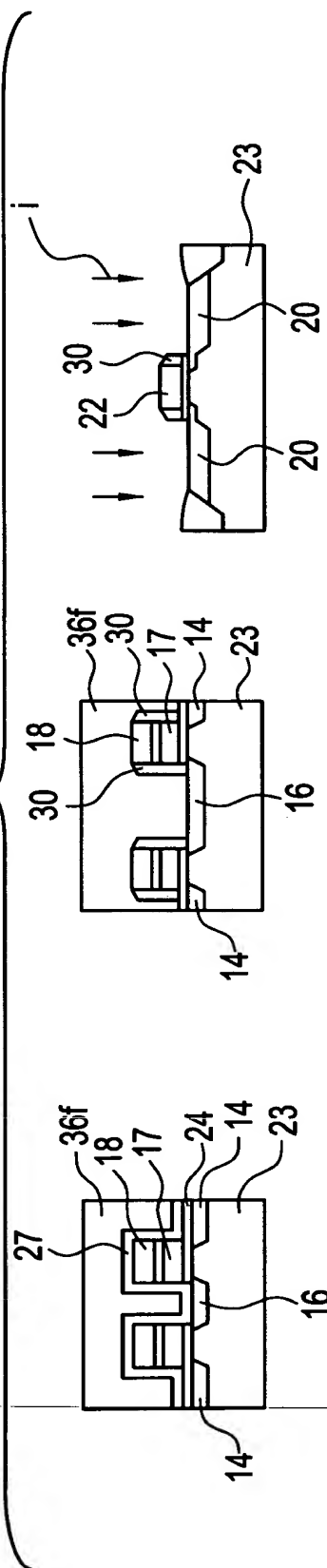
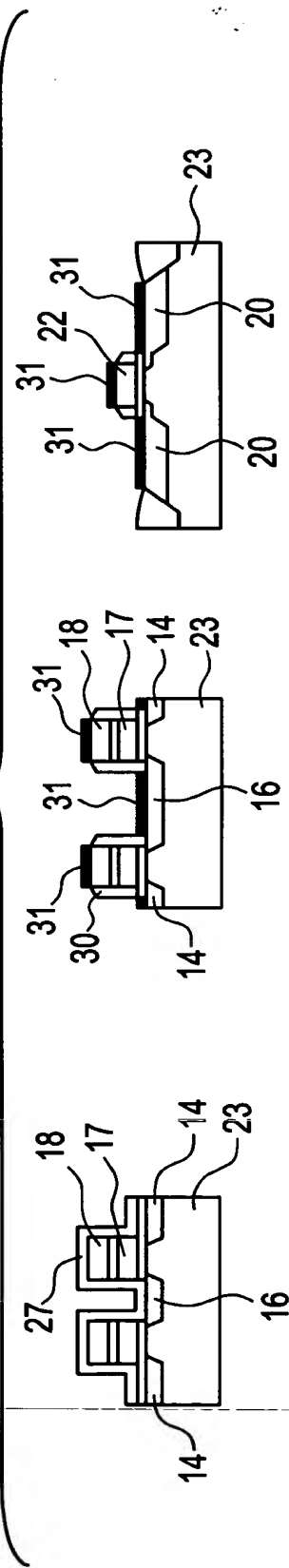
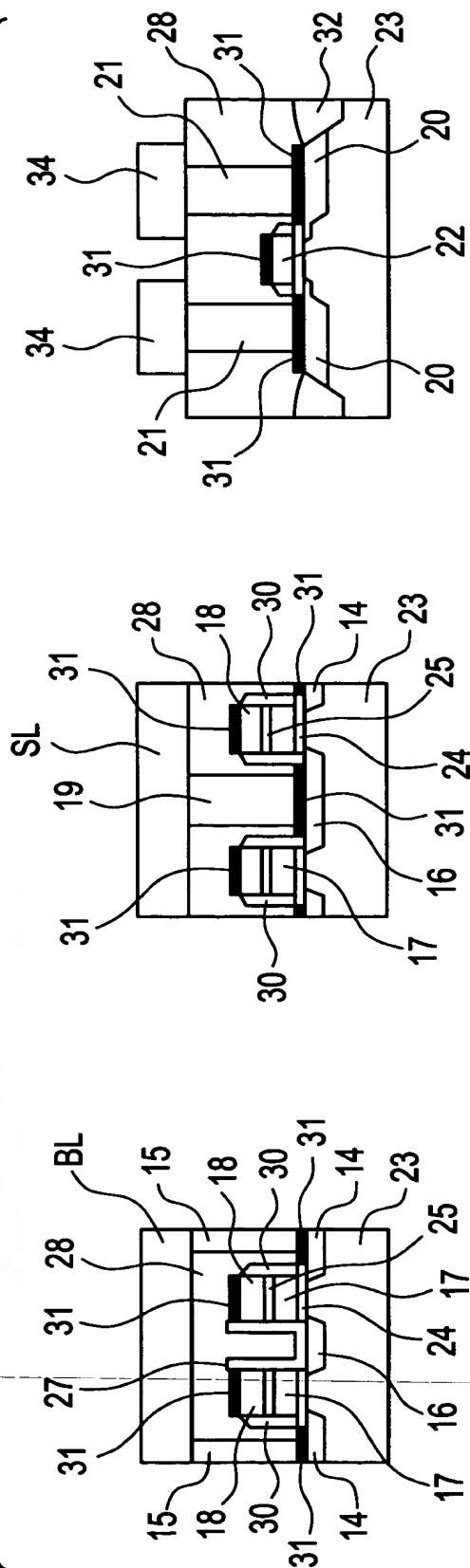


FIG. 6K



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**FIG. 7**



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12/20

FIG. 8A

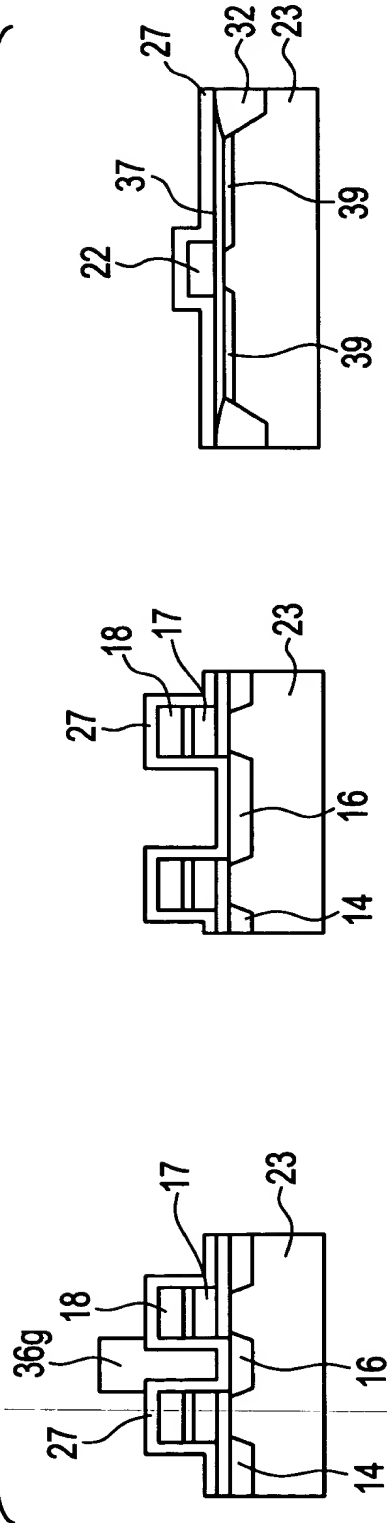
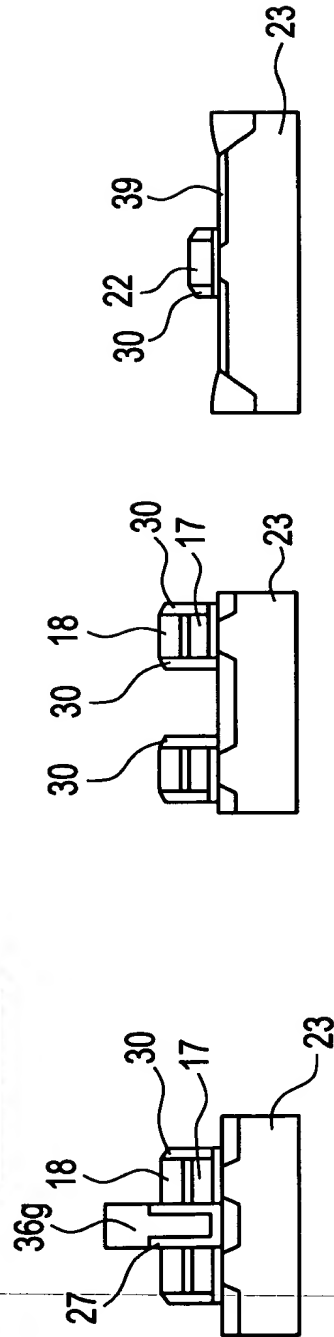


FIG. 8B



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13/20

FIG. 8C

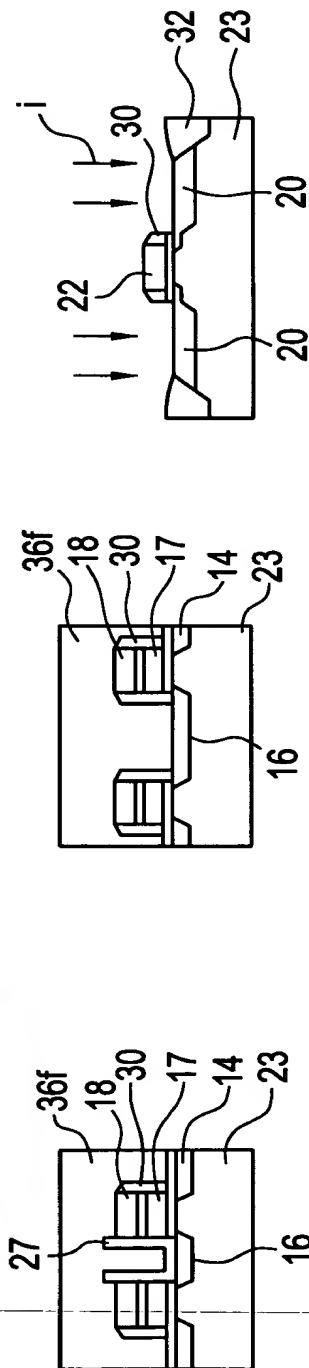
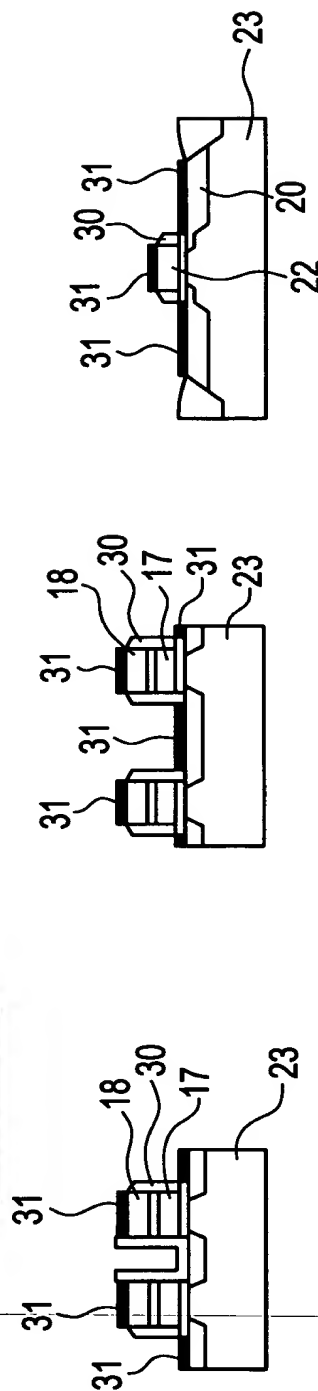


FIG. 8D

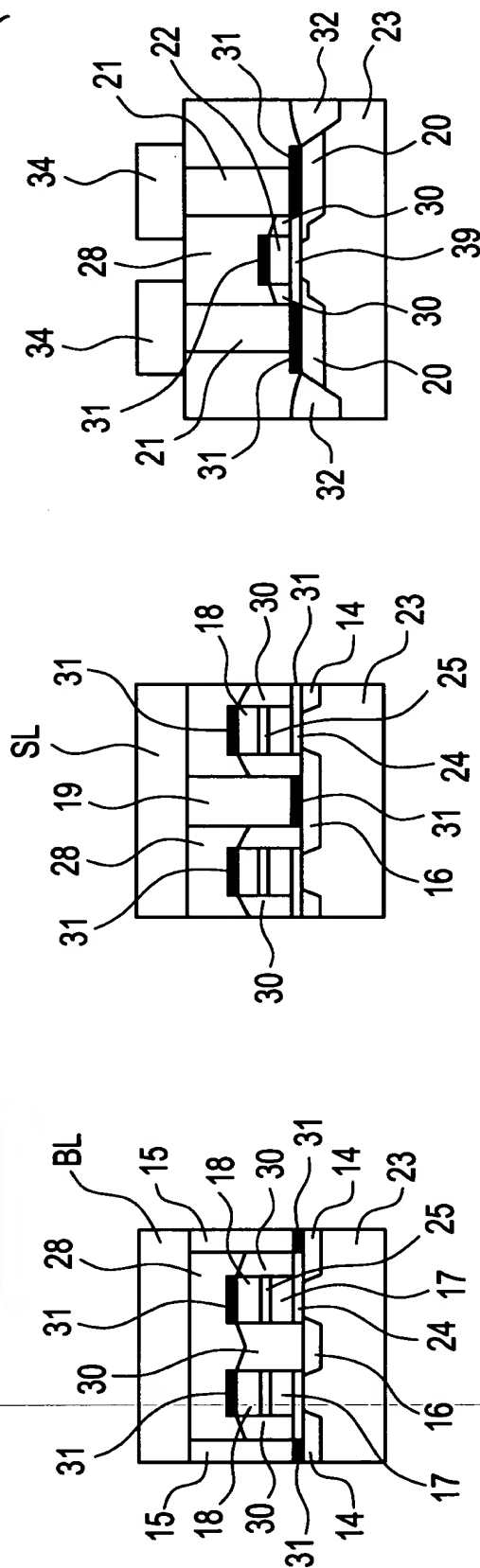


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14/20

9. G. F.



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15/20

FIG. 10A

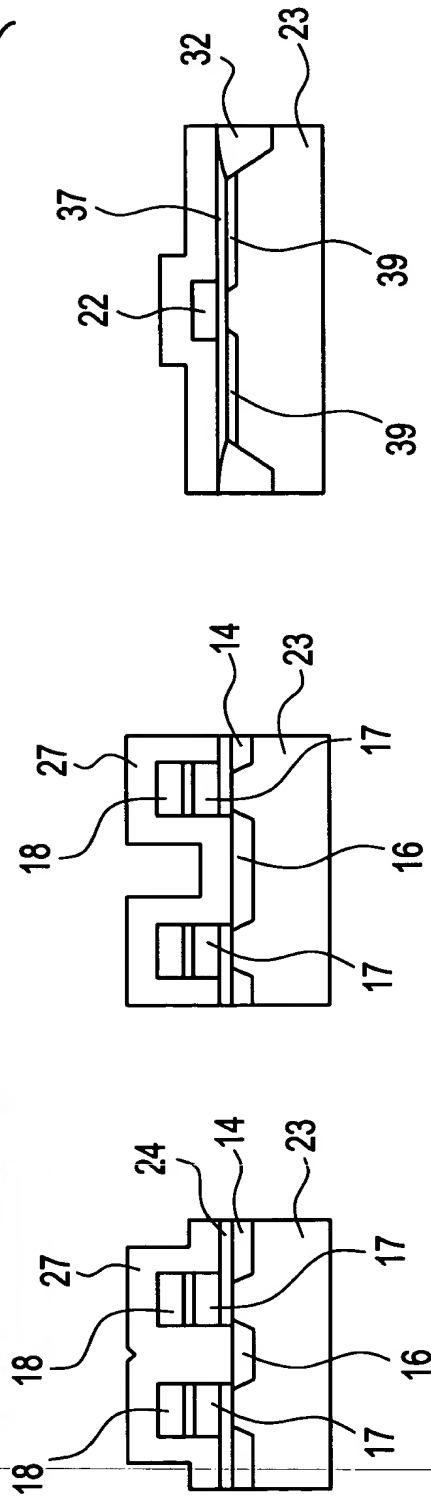


FIG. 10B

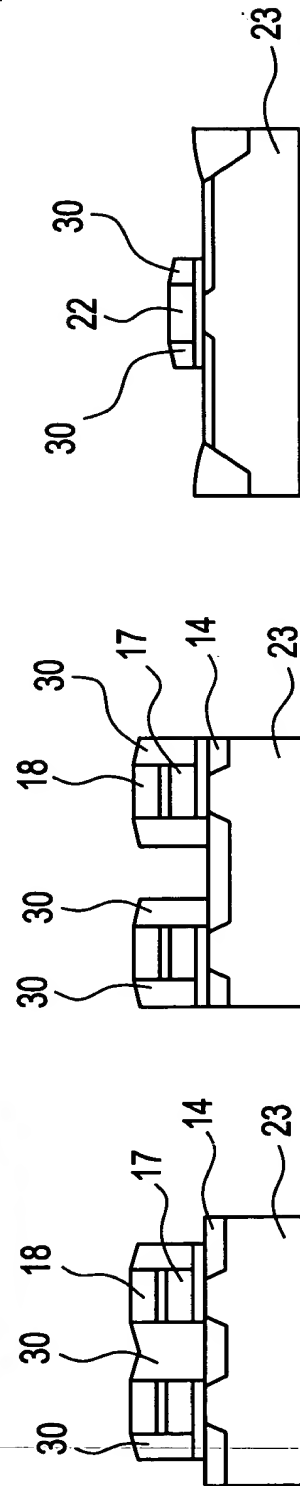


FIG. 10C

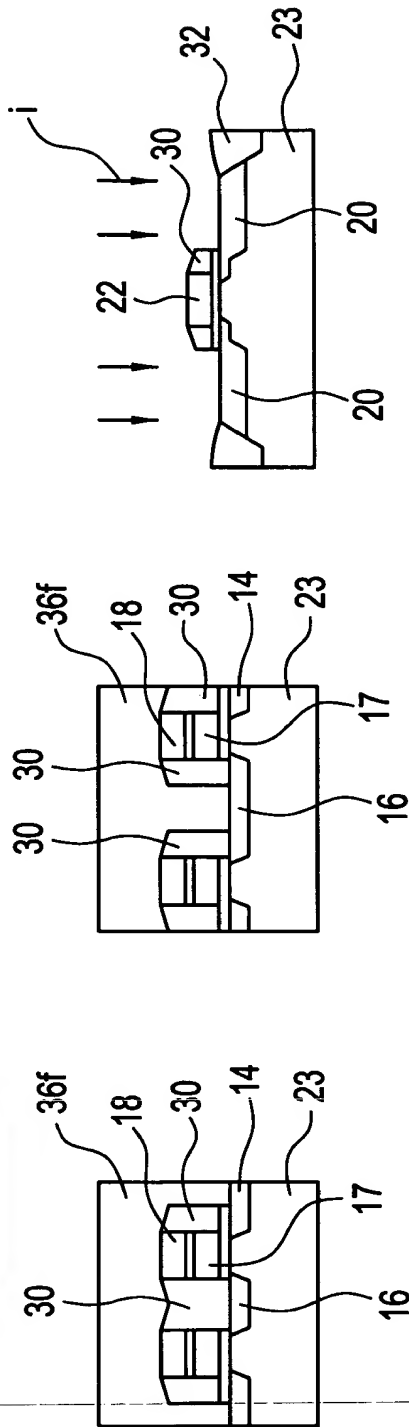
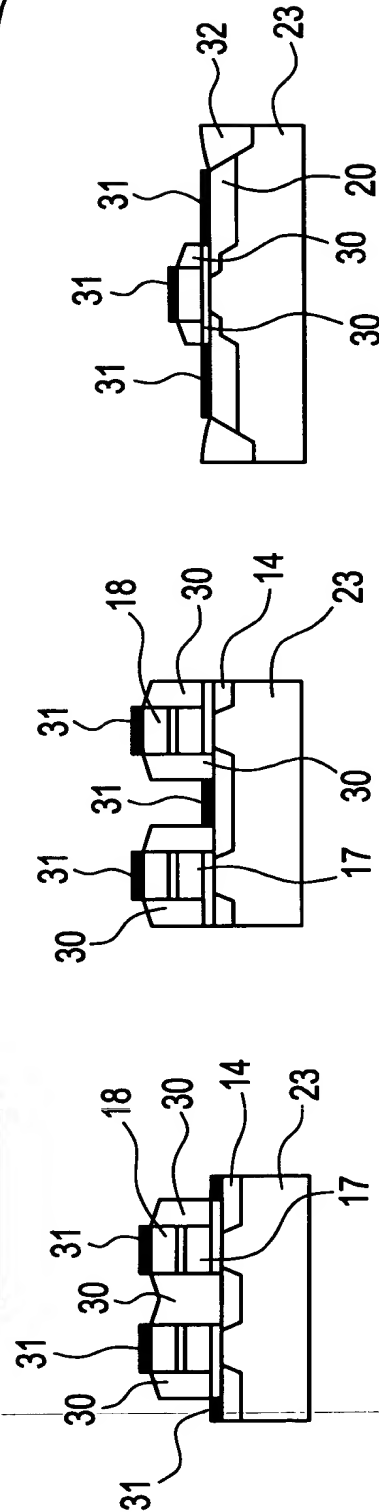


FIG. 10D



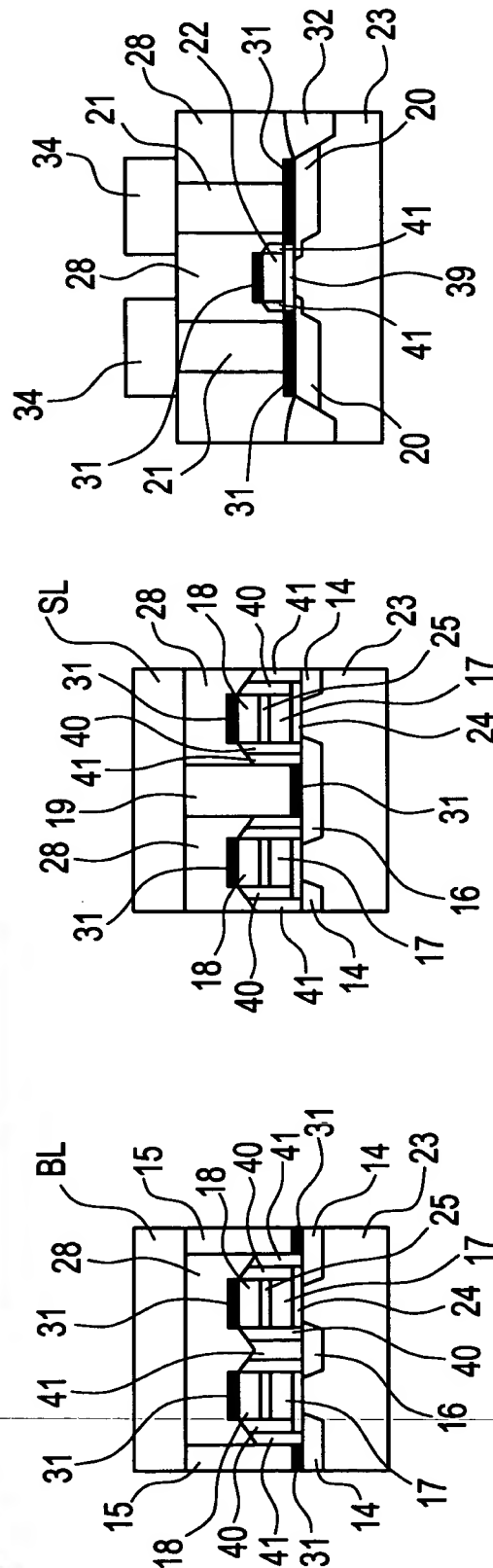


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17/20

FIG. 11



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18/20

FIG. 12A

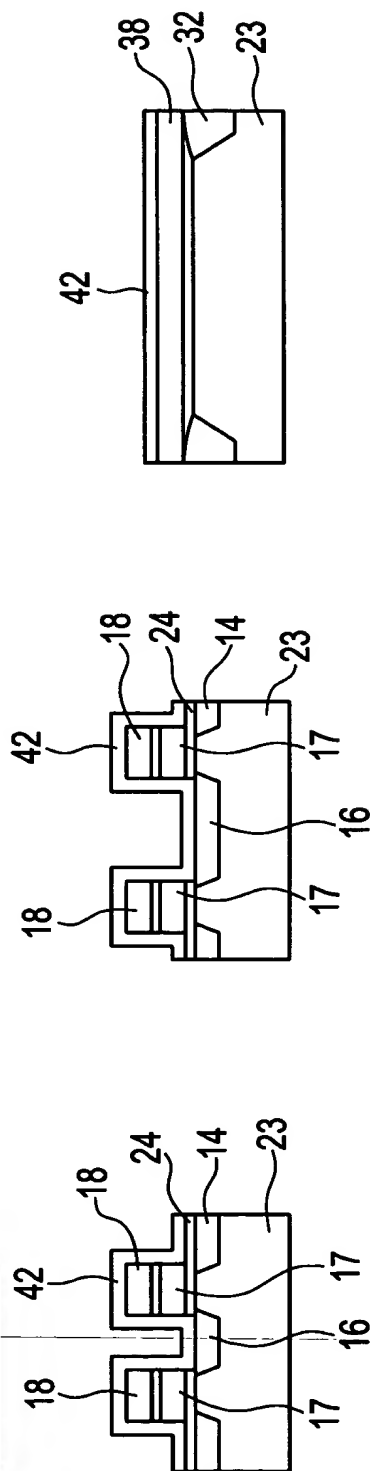
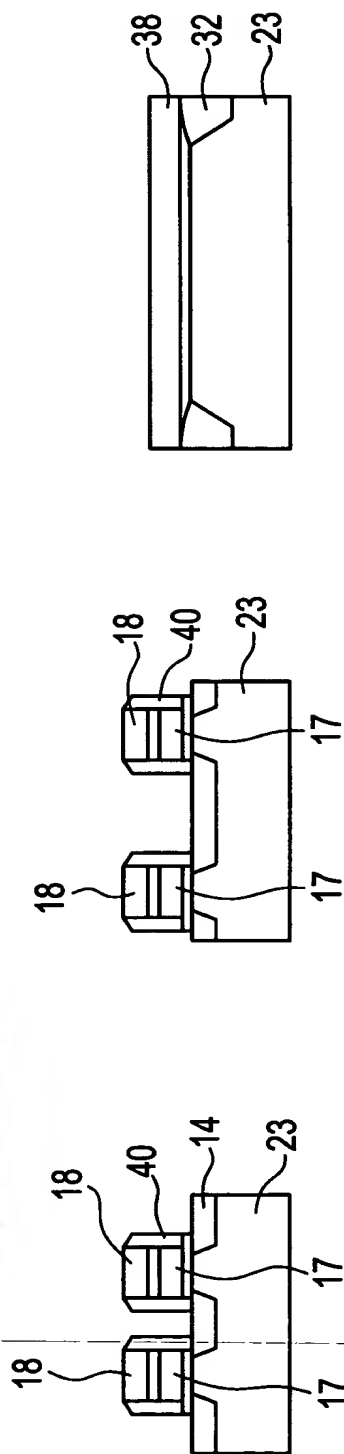


FIG. 12B



APPROVED	O.G. FIG.	
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Q62964---Filed May 25, 2001

19/20

FIG. 12C

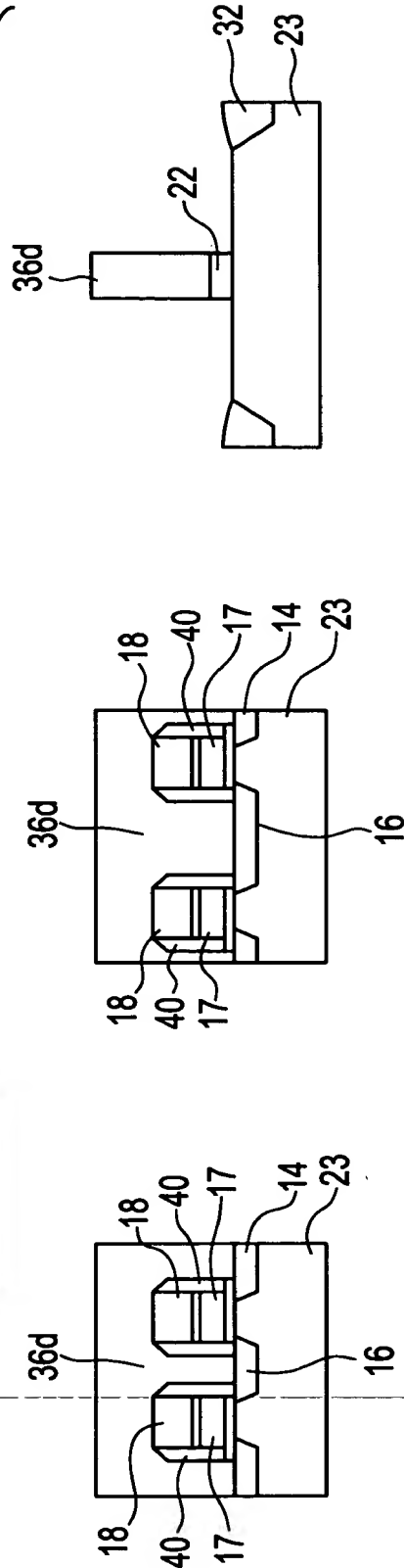


FIG. 12D

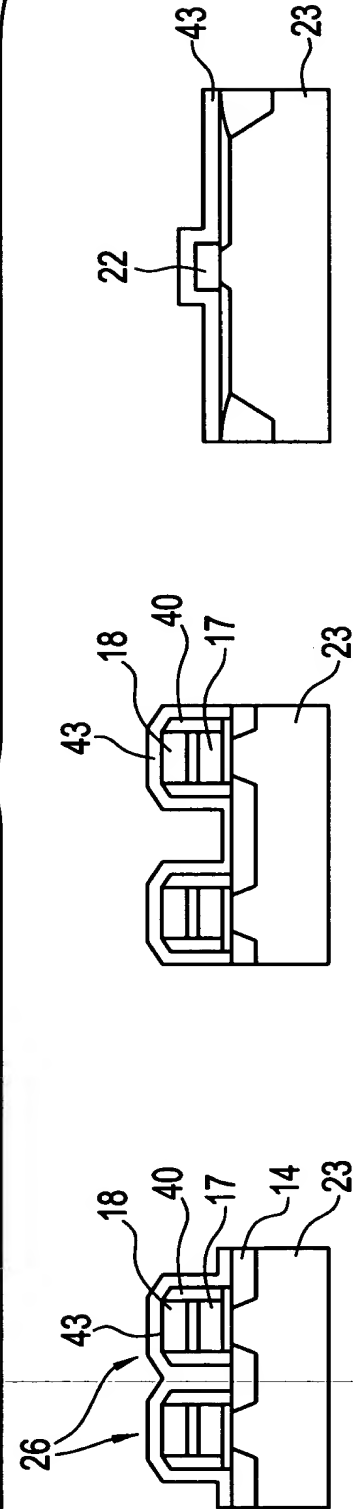


FIG. 12E

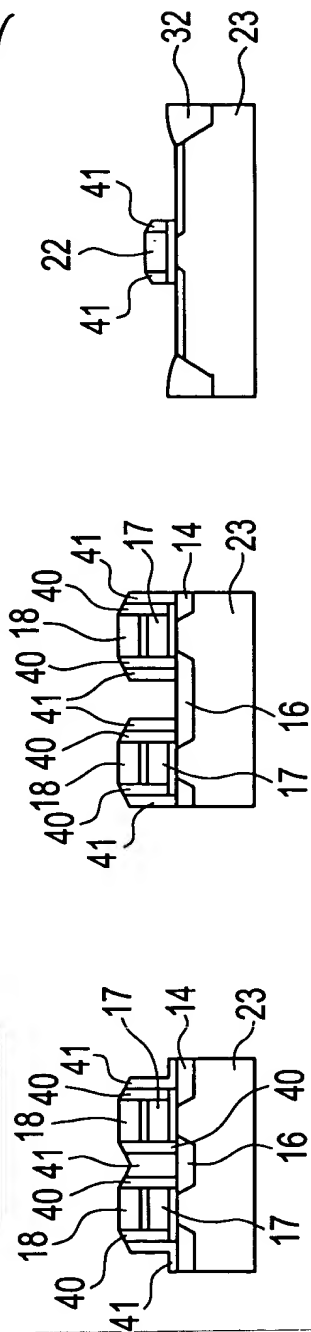


FIG. 12F

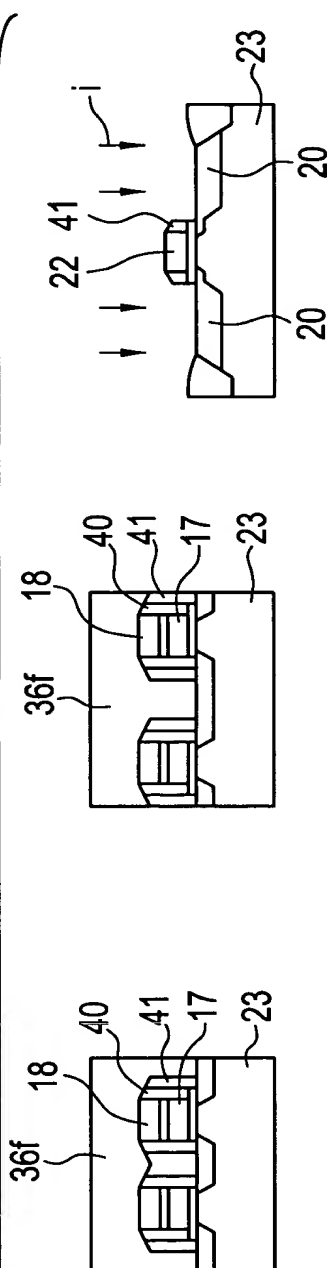


FIG. 12G

